



PATENT
Atty. Dkt. No. AMAT/4227.P1/DSM/BCVD/JW

1752
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Latchford, et al.

Serial No.: 09/921,938

Confirmation No.: 8367

Filed: August 2, 2001

For: Photolithography Scheme
Using a Silicon Containing
Resist

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

§§§§§ Group Art Unit: 1752

§§§§§ Examiner: Amanda Walke

CERTIFICATE OF MAILING 37 CFR 1.8	
I hereby certify that this correspondence is being deposited on <u>3/3/04</u> , 2004 with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.	
Date <u>3/3/04</u>	Signature

RESPONSE TO OFFICE ACTION DATED SEPTEMBER 3, 2003

In response to the Office Action dated September 3, 2003, having a shortened statutory period for response extended three months to expire on March 3, 2004, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/4227.P1/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper. **Remarks/Arguments** begin on page 7 of this paper.